

April 9, 2004

To: Commissioner of Patents and Trademarks  
Washington, D.C. 20231.

Fr: George O. Saile     Reg. No. 19,572  
28 Davis Avenue  
Poughkeepsie, N.Y. 12603

Subject:

**Continuaton of**  
Serial No.: 10/411,347 4/10/03  
  
KUO-CHI TU, CHUN-YAO CHEN, HUEY-CHI CHU  
  
METHOD OF FABRICATING AN EMBEDDED DRAM  
FOR METAL-INSULATOR-METAL (MIM) CAPACITOR  
STRUCTURE

**PRELIMINARY AMENDMENT**

Dear Sir:

This is a preliminary amendment for the above referenced Continuation. Please  
amend the above identified application for patent as follows:

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States  
Postal Service as first class mail in an envelope addressed to: Commissioner of Patents  
and Trademarks, Washington, D.C. 20231, on April 9, 2004.

Stephen B. Ackerman, Reg. No. 37,761

Signature/Date



4/9/04

March 30, 2004

To: Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Fr: Stephen B. Ackerman, Reg. No. 37,761  
28 Davis Avenue  
Poughkeepsie, N.Y. 12603

Subject: CONTINUATION PATENT APPLICATION OF

Serial No. 10/411347  
Filing Date 4/10/03

K. C. TU ET AL

"METHOD OF FABRICATING AN  
EMBEDDED DRAM FOR METAL-  
INSULATOR-METAL (MIM) CAPACITOR  
STRUCTURE"

PRELIMINARY AMENDMENT

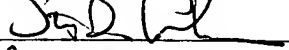
Dear Sir:

Please amend the above identified application for patent as follows:

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on April 9, 2004.

Stephen B. Ackerman, Reg. No. 37,761

Signature   
Date April 9, 2004

Amendments to the Specification begin on page 3 of this paper.

Amendments to the Claims are reflected in the listing of the Claims which begins on page 4 of this paper.

Remarks/Arguments begin on page 9 of this paper.

TS01-1440C

IN THE TITLE

Please amend the title as follows:

~~METHOD OF FABRICATING AN EMBEDDED DRAM FOR METAL-INSULATOR-~~  
METAL (MIM) CAPACITOR STRUCTURE